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	Application No.	Applicant(s)	
Notice of Allowability	10/612,904	WARGO ET AL.	
	Examiner	Art Unit	
	Sing P. Chan	1734	
The MAILING DATE of this communication appe All claims being allowable, PROSECUTION ON THE MERITS IS	ars on the cover sheet w	rith the correspondence addressin this application. If not included	
herewith (or previously mailed), a Notice of Allowance (PTOL-85) NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT RI of the Office or upon petition by the applicant. See 37 CFR 1.313	GHTS. This application is	nunication will be mailed in due cour subject to withdrawal from issue at	se. <b>THIS</b> the initiative
1. This communication is responsive to <u>an amendment filed o</u>	n October 3, 2005.		
2. ☑ The allowed claim(s) is/are <u>1-20</u> .			
<ul><li>3. ☐ Acknowledgment is made of a claim for foreign priority un</li><li>a) ☐ All b) ☐ Some* c) ☐ None · of the:</li></ul>	der 35 U.S.C. § 119(a)-(d	or (f).	
<ol> <li>Certified copies of the priority documents have</li> </ol>	been received.	•	
<ol><li>Certified copies of the priority documents have</li></ol>	been received in Applicat	ion No	
<ol><li>Copies of the certified copies of the priority doc</li></ol>	cuments have been receive	ed in this national stage application	from the
International Bureau (PCT Rule 17.2(a)).			
* Certified copies not received:			
Applicant has THREE MONTHS FROM THE "MAILING DATE" on noted below. Failure to timely comply will result in ABANDONM THIS THREE-MONTH PERIOD IS NOT EXTENDABLE.	of this communication to fi ENT of this application.	e a reply complying with the require	ments
4. A SUBSTITUTE OATH OR DECLARATION must be submi INFORMAL PATENT APPLICATION (PTO-152) which give	tted. Note the attached Exs reason(s) why the oath	CAMINER'S AMENDMENT or NOTIC or declaration is deficient.	CE OF .
5. CORRECTED DRAWINGS (as "replacement sheets") mus	t be submitted.	•	
(a) ☐ including changes required by the Notice of Draftsperson		w ( PTO-948) attached	
1) 🗌 hereto or 2) 🔲 to Paper No./Mail Date	ار المحاليس إلى المحاليس المح المحاليس المحاليس ال	e e	
(b) ☐ including changes required by the attached Examiner's Paper No./Mail Date	Amendment / Comment of	or in the Office action of	
Identifying indicia such as the application number (see 37 CFR 1. each sheet. Replacement sheet(s) should be labeled as such in the	84(c)) should be written on ne header according to 37 C	the drawings in the front (not the bac FR 1.121(d).	k) of
6. DEPOSIT OF and/or INFORMATION about the depose attached Examiner's comment regarding REQUIREMENT F	sit of BIOLOGICAL MAT FOR THE DEPOSIT OF B	ERIAL must be submitted. Note OLOGICAL MATERIAL.	the
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Attachment(s)			
1. Notice of References Cited (PTO-892)	5. Notice of I	nformal Patent Application (PTO-15	2)
2. Notice of Draftperson's Patent Drawing Review (PTO-948)		6. ☐ Interview Summary (PTO-413), Paper No./Mail Date	
3. Information Disclosure Statements (PTO-1449 or PTO/SB/08 Paper No./Mail Date	8), 7. ☐ Examiner's	s Amendment/Comment	
<ol> <li>Examiner's Comment Regarding Requirement for Deposit of Biological Material</li> </ol>	8. 🛭 Examiner	s Statement of Reasons for Allowan	ce
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## **DETAILED ACTION**

## **Drawings**

1. Drawings as filed on October 3, 2005 are acceptable by the examiner.

## Allowable Subject Matter

- 2. Claims 1-20 are allowed.
- 3. The following is an examiner's statement of reasons for allowance: The claims recite a method of forming high-resolution electronic circuits on a substrate. The method includes laminating an upper surface of the substrate with a layer of dielectric film. Laser drilling the upper surface of the dielectric film to form at least one channel. filling the channel with an electrically conductive material, applying a release layer to the upper surface of the dielectric film with the lower surface of the release layer is coated with an adhesive layer and adhering to the upper surface of the dielectric film, heating the substrate, the dielectric film, electrically conductive material in the channel, and the release layer to a temperature in a range of 150°C to 175°C to enhance the mechanical integrity of the conductive material within the channel and to create permanent adhesion between conductive material and the upper surface of the substrate, and removing the release layer and the dielectric film adhered to the substrate and exposing the electrically conductive material formed patterned and remained permanently on the upper surface of the substrate. Koste et al discloses a method forming metal pattern on dielectric substrates. The method includes providing a dielectric substrate, laminating a thin organic layer, preferably MYLAR, (Col 4, lines 7-9) which is polyethylene teraphthalate polyester, i.e. a dielectric film (Col 4, lines 55-56), using either an electron

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beam or a laser as an energy beam source to form a plurality of holes and channels (Col 4, lines 44-54), depositing a wet metal material, i.e. conductive material, over the organic mask, i.e. the organic layer to form metallized channel and interconnection holes by rolling, wiping, and doctor blading (Col 5, lines 17-22), stripping the organic mask by peeling to remove undesired metal (Col 5, lines 39-45), and then firing according to well known techniques (Col 5, lines 46-50). Koste et al is silent as to applying a release layer with adhesive coating to the upper surface of the dielectric film and removing the release layer and the dielectric film, exposing electrically conductive material on the upper surface of the substrate and heating the substrate, the dielectric film, the electrically conductive material within the channel, and the release layer to a temperature in a range of 150°C to 175°C to enhance the mechanical integrity of the conductive material within the channel and to create permanent adhesion between conductive material and the upper surface of the substrate, and then removing the release layer and the dielectric film adhered to the substrate and exposing the electrically conductive material formed patterned and remained permanently on the upper surface of the substrate. A search of the prior arts of record did not disclose

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Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."

reference or references in combination with the recited features.

the right to a control of supplied attention

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Any inquiry concerning this communication or earlier communications from the examiner should be directed to Sing P. Chan whose telephone number is 571-272-1225. The examiner can normally be reached on Monday-Thursday 7:30AM-11:00AM and 12:00PM-4:00PM.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Christopher A. Fiorilla can be reached on 571-272-1187. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

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CHRIS FIORILLA SUPERVISORY PATENT EXAMINER

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